(11) **EP 2 345 925 A3**

(12)

EUROPEAN PATENT APPLICATION

(88) Date of publication A3: **22.02.2012 Bulletin 2012/08**

(51) Int Cl.: **G02F 1/1335** (2006.01)

G02F 1/1362 (2006.01)

(43) Date of publication A2: 20.07.2011 Bulletin 2011/29

(21) Application number: 11157148.5

(22) Date of filing: 05.08.2002

(84) Designated Contracting States: **DE FI FR GB NL**

(30) Priority: 06.08.2001 JP 2001237887

(62) Document number(s) of the earlier application(s) in accordance with Art. 76 EPC: 02017478.5 / 1 284 433

(71) Applicant: NLT Technologies, Ltd. Nakahara-ku Kawasaki Kanagawa 211-8666 (JP)

(72) Inventors:

 Sakamoto, Michiaki Tokyo (JP) Ihida, Satoshi Tokyo (JP)

 Ikeno, Hidenori Tokyo (JP)

 Shinohara, Masaki Tokyo (JP)

 Kimura, Shigeru Tokyo (JP)

 Morio, Kenji Tokyo (JP)

 Saeki, Kazurou Tokyo (JP)

(74) Representative: Samson & Partner Widenmayerstrasse 5 80538 München (DE)

(54) Transflective liquid crystal display and method for manufacturing the same

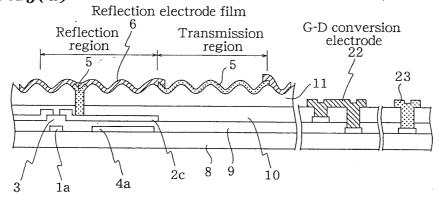
(57) A method for manufacturing a transflective type active matrix substrate comprising the steps of depositing a passivation film (10) on a substrate on scanning lines and signal lines and forming a first contact hole in a portion, G-D conversion portion, which is provided around said substrate to lead out a signal line, and filling said first contact hole with a predetermined conductive material, and

depositing an organic film both in a transmission region

and a reflection region, then forming irregularities on the surface and removing the organic film on a terminal of a switching element to form a second contact hole, and forming a transparent electrode film in the transmission region, and

forming a reflection electrode film (16) overlapping with the transparent electrode film around an overall periphery to interconnect the terminal and the reflection electrode film (6) through the second contact hole.

FIG.15(d)





PARTIAL EUROPEAN SEARCH REPORT

Application Number

under Rule 62a and/or 63 of the European Patent Convention. This report shall be considered, for the purposes of subsequent proceedings, as the European search report

EP 11 15 7148

[01 4001510 4 710 11 05 711					
Category	Citation of document with indication of relevant passages	n, wnere appropriate,	Relevant to claim	CLASSIFICATION OF THE APPLICATION (IPC)		
Х	JP 2001 194662 A (NEC C 19 July 2001 (2001-07-1 * the whole document *	ORP) 9)	1	INV. G02F1/1335		
	& US 2004/070709 A1 (KA AL) 15 April 2004 (2004 * the whole document *	NOU HIROSHI [JP] ET -04-15) 		ADD. G02F1/1362		
				TECHNICAL FIELDS		
				SEARCHED (IPC)		
				G02F		
INCO	IPLETE SEARCH					
	h Division considers that the present applicati with the EPC so that only a partial search (R					
Claims sea	arched completely :	•				
Claims sea	arched incompletely :					
	searched:					
	r the limitation of the search: Sheet C					
	Place of search	Date of completion of the search		Examiner		
	Munich	23 December 2011	Wo1	frum, Georg		
X : parti Y : parti docu	TEGORY OF CITED DOCUMENTS cularly relevant if taken alone cularly relevant if combined with another ment of the same category	T : theory or principle E : earlier patent doc after the filing dat D : document cited L : document cited fo	ument, but publi e i the application ir other reasons	shed on, or		
A : techi	nological background written disclosure		& : member of the same patent family, corresponding document			



INCOMPLETE SEARCH SHEET C

Application Number

EP 11 15 7148

Claim(s) completely searchable:

Claim(s) not searched: 2^{-4}

Reason for the limitation of the search (non-patentable invention(s)):

Three independent method claims which contravene Rule 43(2) EPC have been identified in the present application, namely claims 1 to 3. After the invitation in accordance with Rule 62a(1) EPC to indicate the independent method claim on the basis of which the search is to be carried out, the applicant has submitted an amended set of claims 1-4 with his reply dated 19.07.2011. This amended set of claims is apparently based on claims 1-4 as originally filed. However, the applicant may not amend the description, claims and drawings of his European patent application before receiving the European search report according to Rule 137(1) EPC. Therefore, the amended set of claims 1-4 cannot be searched. However, the submission of the applicant has to be understood as an indication that the applicant wants to receive a European search report for claim 1 as originally filed.

Therefore, no European search report has been drawn up for independent device claims 2 and 3 in accordance with Rule 62a(1) EPC. Thus, their subject-matter is regarded as unsearched subject-matter. The European search opinion is established for the subject-matter of claim 1 only.

ANNEX TO THE EUROPEAN SEARCH REPORT ON EUROPEAN PATENT APPLICATION NO.

EP 11 15 7148

This annex lists the patent family members relating to the patent documents cited in the above-mentioned European search report. The members are as contained in the European Patent Office EDP file on The European Patent Office is in no way liable for these particulars which are merely given for the purpose of information.

23-12-2011

Patent document cited in search report		Publication date		Patent family member(s)	Publication date
JP 2001194662	A	19-07-2001	JP KR KR TW US	2001194662 A 20010086334 A 20040062478 A I238280 B 2004070709 A1	19-07-2001 10-09-2001 07-07-2004 21-08-2005 15-04-2004

For more details about this annex : see Official Journal of the European Patent Office, No. 12/82

FORM P0459



专利名称(译)	透反液晶显示器及其制造方法				
公开(公告)号	EP2345925A3	公开(公告)日	2012-02-22		
申请号	EP2011157148	申请日	2002-08-05		
[标]申请(专利权)人(译)	NEC液晶技术株式会社				
申请(专利权)人(译)	NEC液晶技术有限公司.				
当前申请(专利权)人(译)	NLT科技有限公司.				
[标]发明人	SAKAMOTO MICHIAKI IHIDA SATOSHI IKENO HIDENORI SHINOHARA MASAKI KIMURA SHIGERU MORIO KENJI SAEKI KAZUROU				
发明人	SAKAMOTO, MICHIAKI IHIDA, SATOSHI IKENO, HIDENORI SHINOHARA, MASAKI KIMURA, SHIGERU MORIO, KENJI SAEKI, KAZUROU				
IPC分类号	G02F1/1335 G02F1/1362 G02B5/08 G02B5/30 G02F1/1333 G02F1/1343 G02F1/136 G02F1/1368 G09F9/30 G09F9/35 H01L21/336 H01L29/786				
CPC分类号	G02F1/133555 G02F1/133504 G02F1/136227 G02F2001/136236				
优先权	2001237887 2001-08-06 JP				
其他公开文献	EP2345925A2				
外部链接	<u>Espacenet</u>				

摘要(译)

一种制造半透半反型有源矩阵基板的方法,包括以下步骤:在扫描线和信号线上的基板上沉积钝化膜(10),并在部分GD转换部分中形成第一接触孔,该部分设置在所述基板周围引出信号线,用预定的导电材料填充所述第一接触孔,并在透射区域和反射区域中沉积有机膜,然后在表面上形成凹凸,并去除端子上的有机膜。开关元件形成第二接触孔,在透射区域形成透明电极膜,并形成与整个周边的透明电极膜重叠的反射电极膜(16),以使端子和反射电极膜互连(6))通过第二个接触孔。

